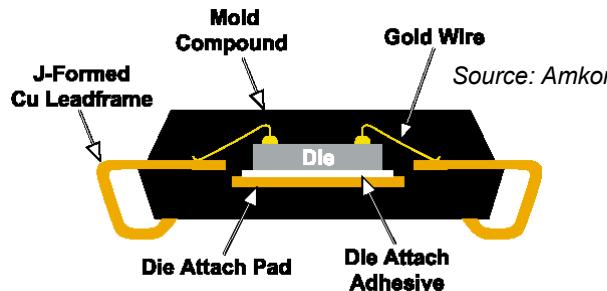


MEMS Packaging and Testing

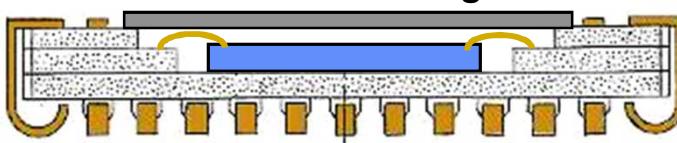
Michael S. Baker
Sandia National Laboratories
msbaker@sandia.gov
October 24th, 2007

MEMS Packaging Considerations

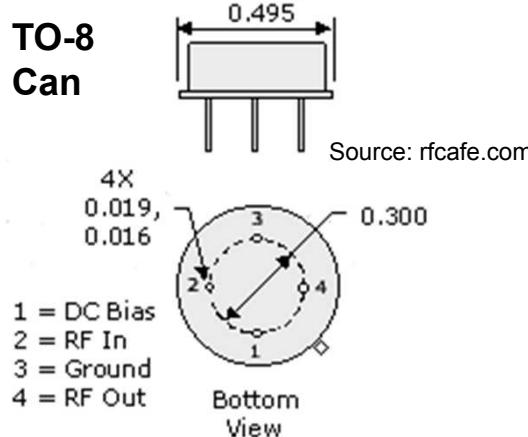
Plastic Leaded Chip Carrier



Ceramic Package



TO-8 Can



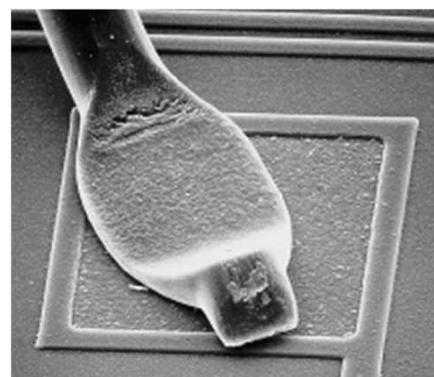
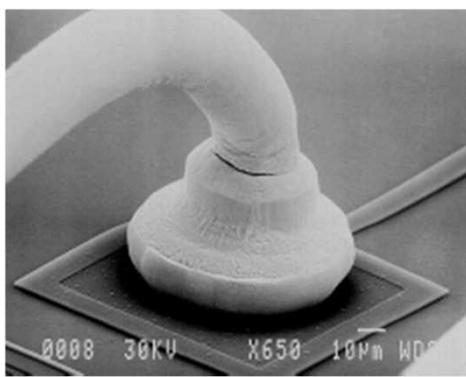
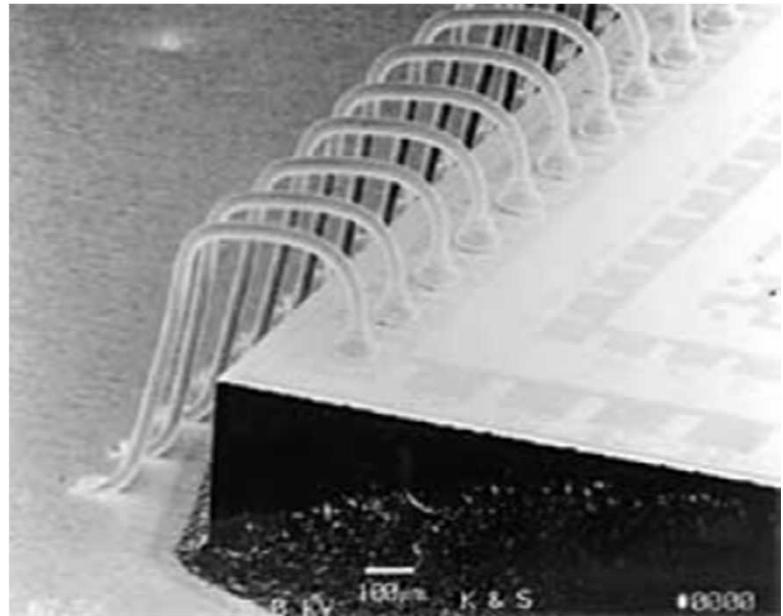
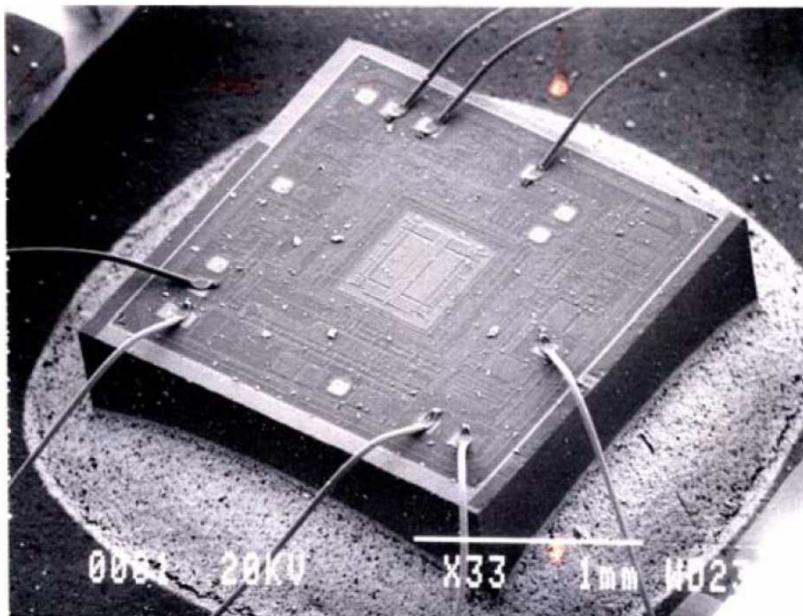
<http://www.amkor.com>

- Estimated that **50%-70%** of MEMS cost is in packaging
- I/C and MEMS Packaging Complexities
 - Electrical (I/O)
 - Thermal (heat dissipation)
 - Mechanical (stress, shock and vibration)
 - Reliability (of both package and device)
- Additional MEMS Specific Concerns
 - Package induced stress and effect on MEMS performance
 - Cleanliness and hermeticity
 - MEMS specific inputs and outputs (optical, fluidic, gas, etc).
 - Very high I/O count (optical)
 - Integration with CMOS

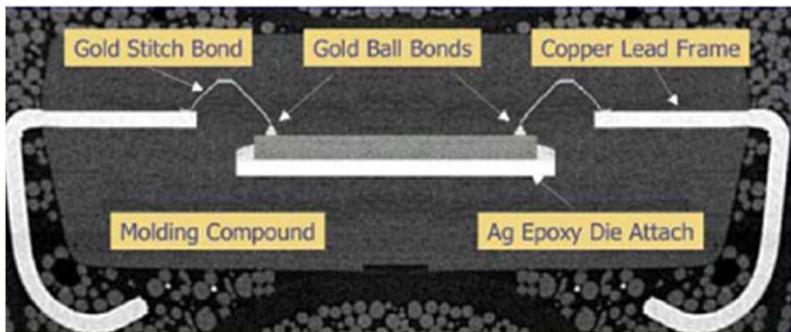


Die attach and wire bond is still the same

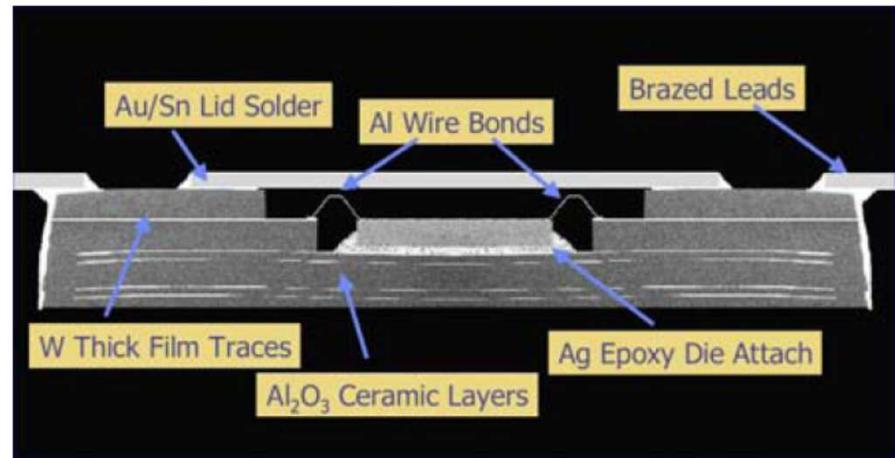
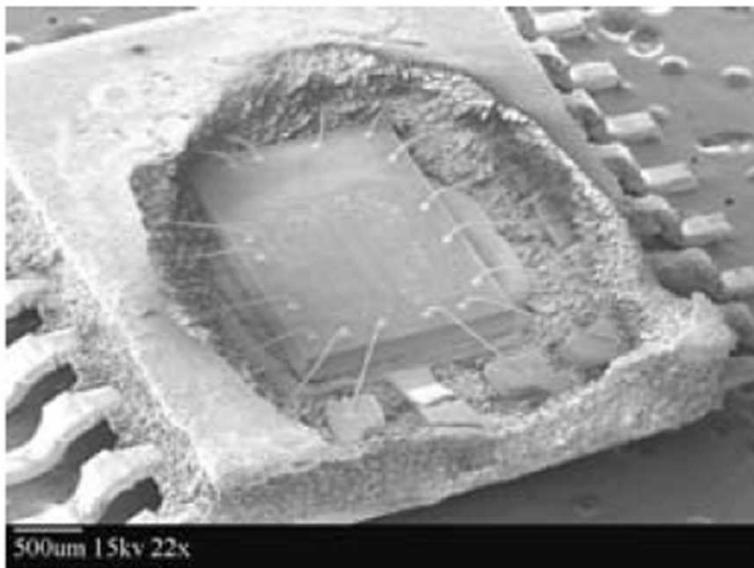
Analog Devices ADXL50



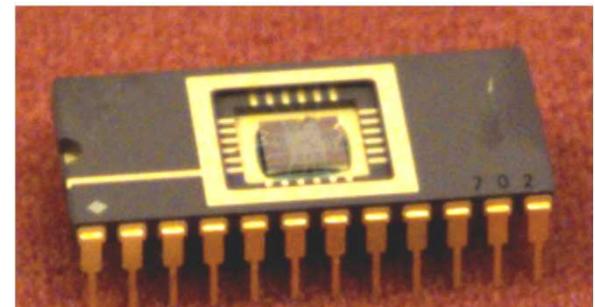
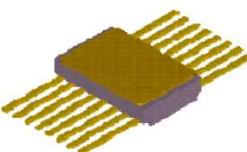
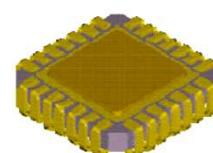
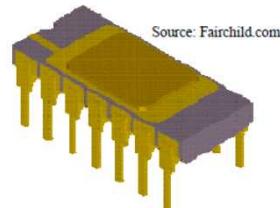
Plastic Packages vs. Ceramic Packages



Analytical Solutions



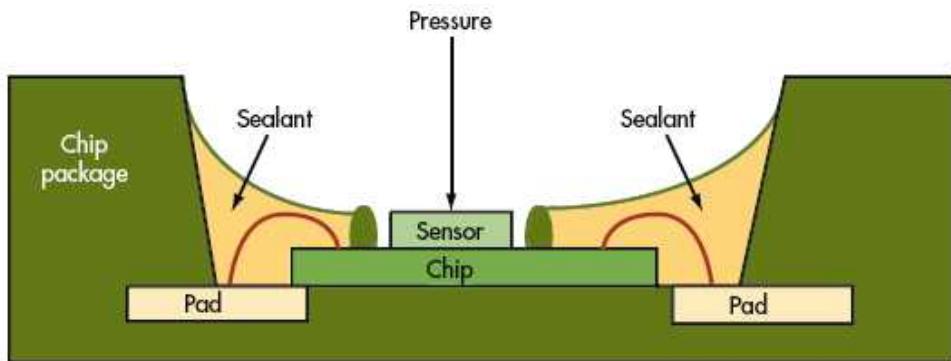
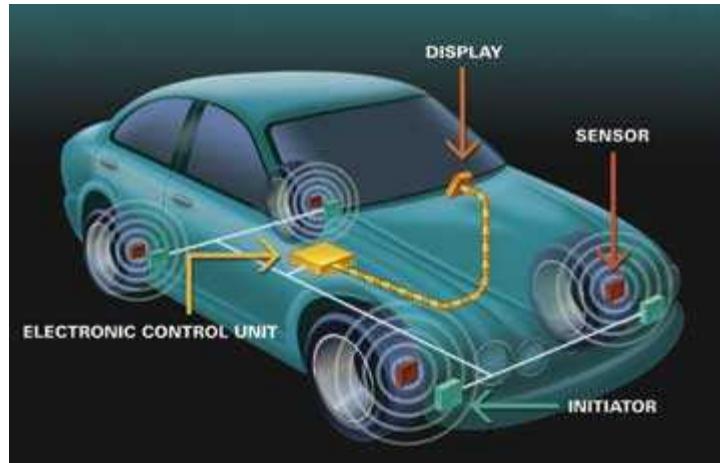
Analytical Solutions



Tire Pressure Monitoring System (TPMS)

John DeGaspari, Mechanical Engineering, ASME, 2005
<http://www.memagazine.org>

MEMS Specific Inputs (gas/pressure)



2. The pressure sensor is the only part of the chip that is exposed. A sealant that is bonded to the chip package protects the components from the harsh environment.





Pressure and Gas Sensors

<http://www.bosch.com>

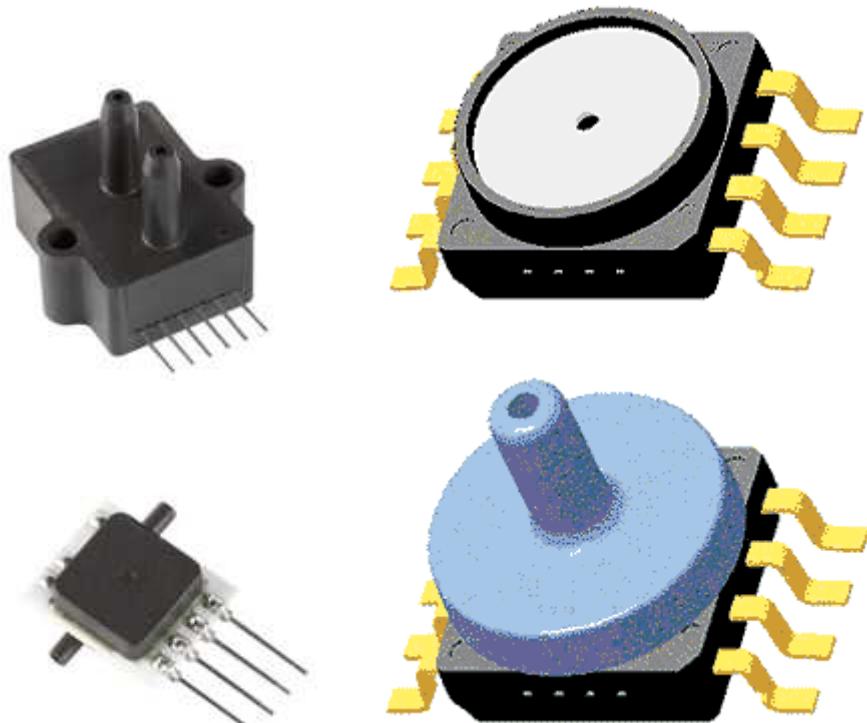


Mass Air Flow Sensor

- **Automotive industry is one of the largest users of MEMS sensors.**

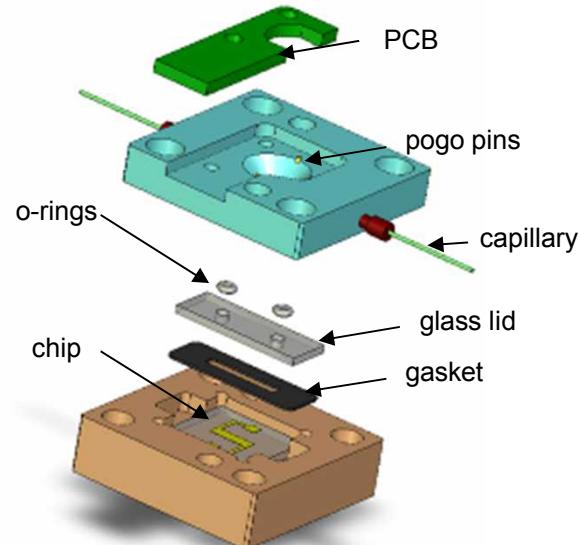
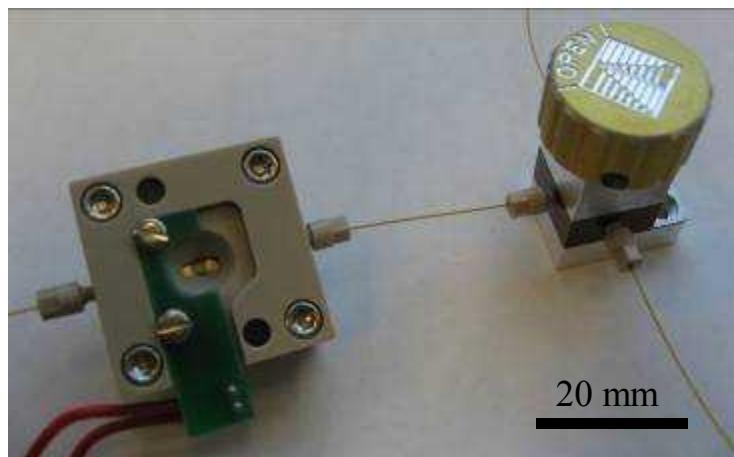
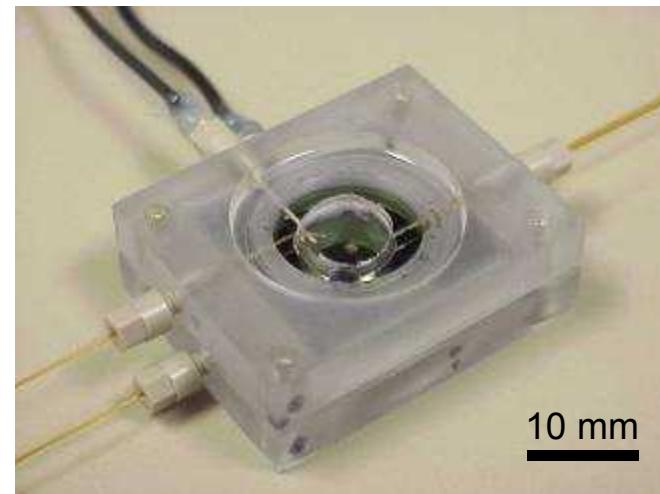
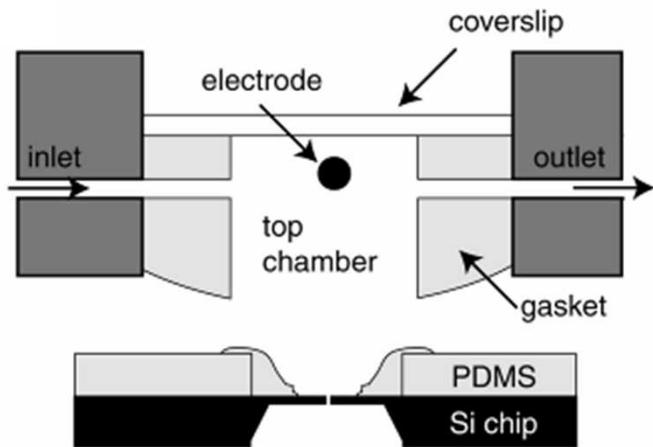


Air Pressure Sensor



<http://www.motorola.com>

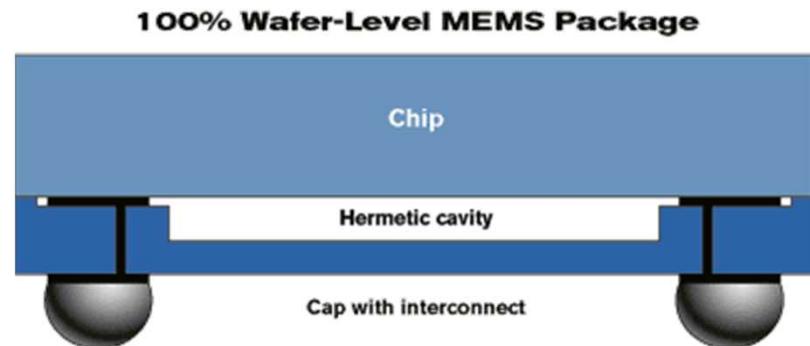
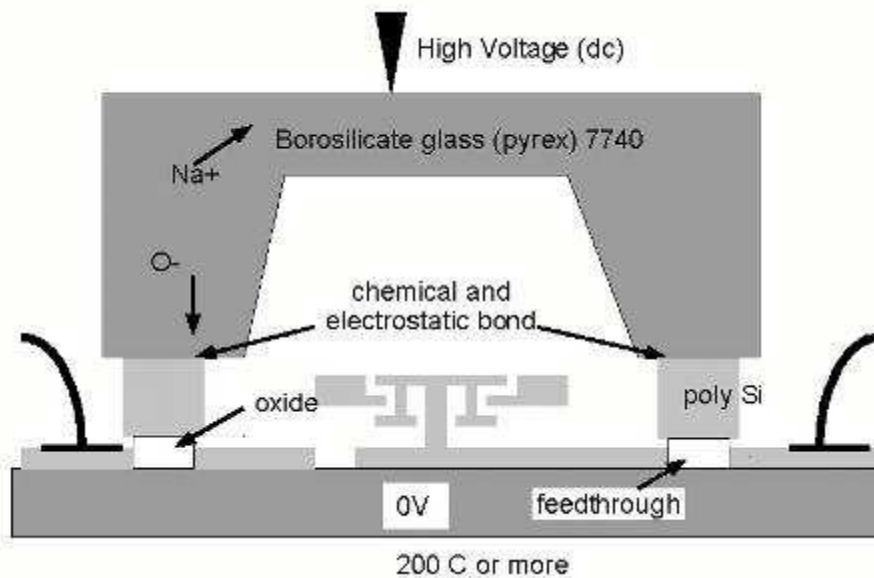
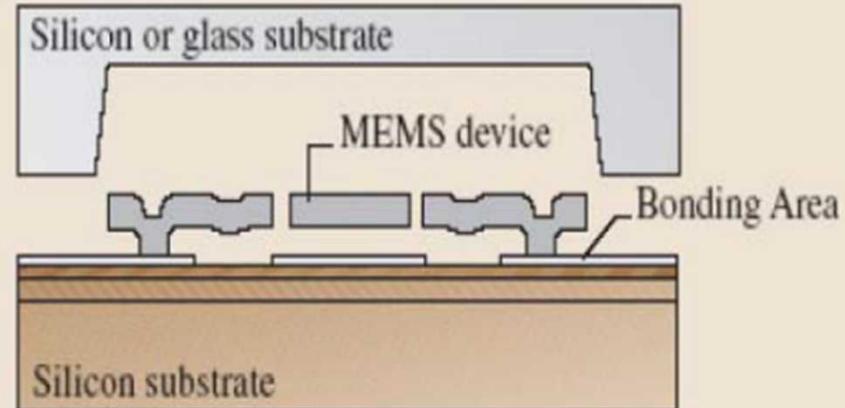
MEMS Specific Inputs (liquids)



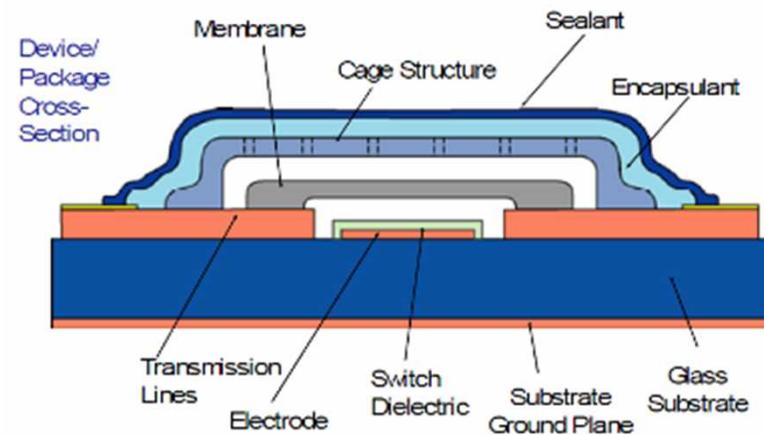
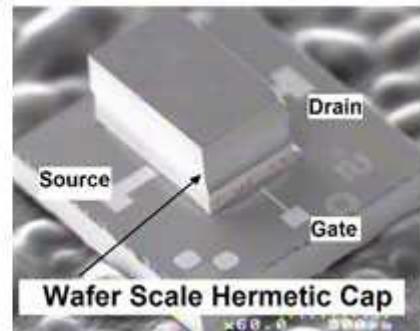
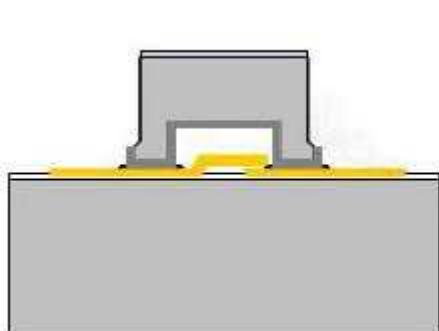
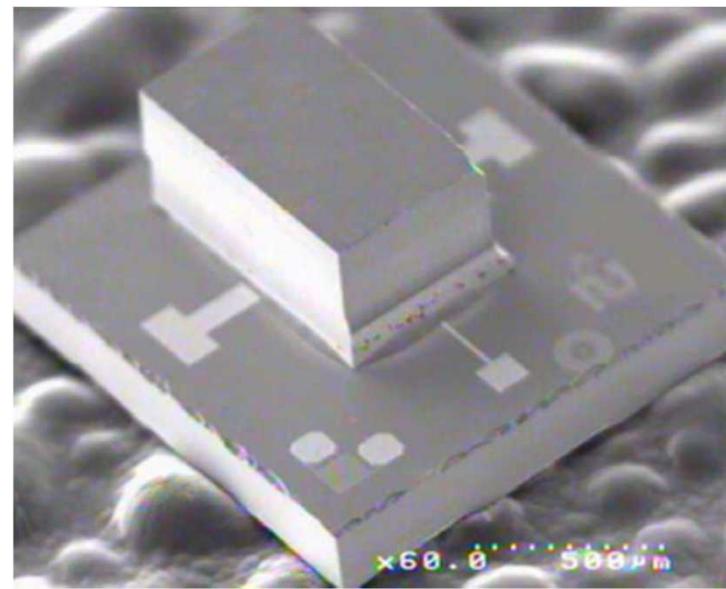
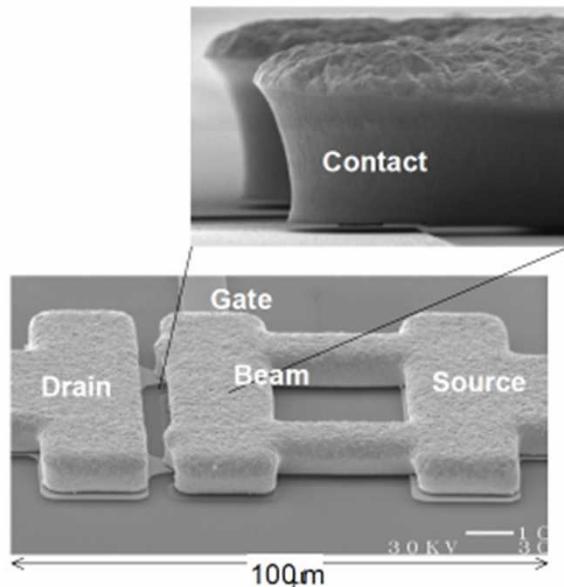
Die/Wafer level packaging

- Die or wafer level
- Protects released MEMS structures from subsequent packaging (plastic packages)
- May allow for wafer level release

Cross-sectional view

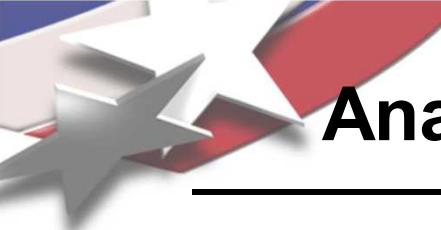


<http://www.radantmems.com>



Cleanliness and Hermeticity

<http://www.memtronics.com>



Analog Devices Accelerometers and Gyro's

- ADXL330 – 3 axis accelerometer. Package is 4 mm x 4 mm x 1.45 mm, priced below \$2 in volume.
- Used in automotive safety systems (airbags)

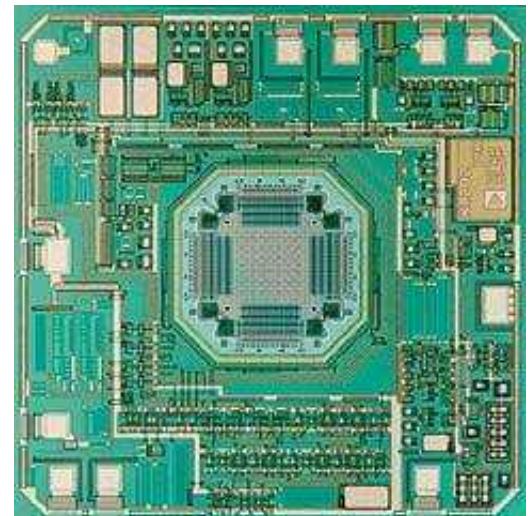
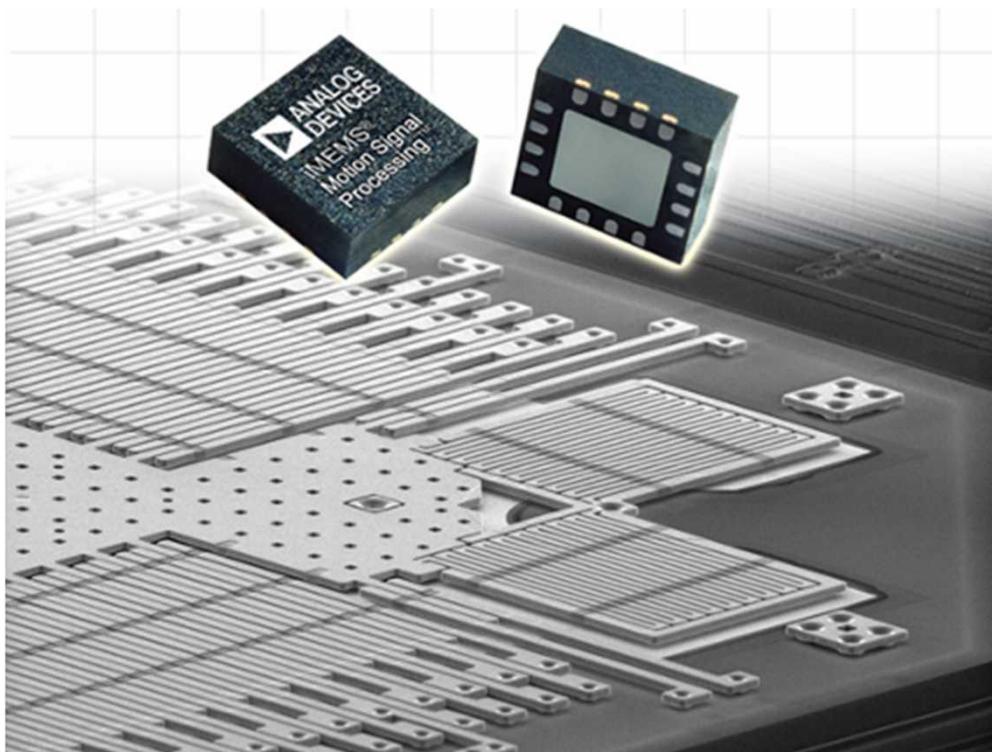
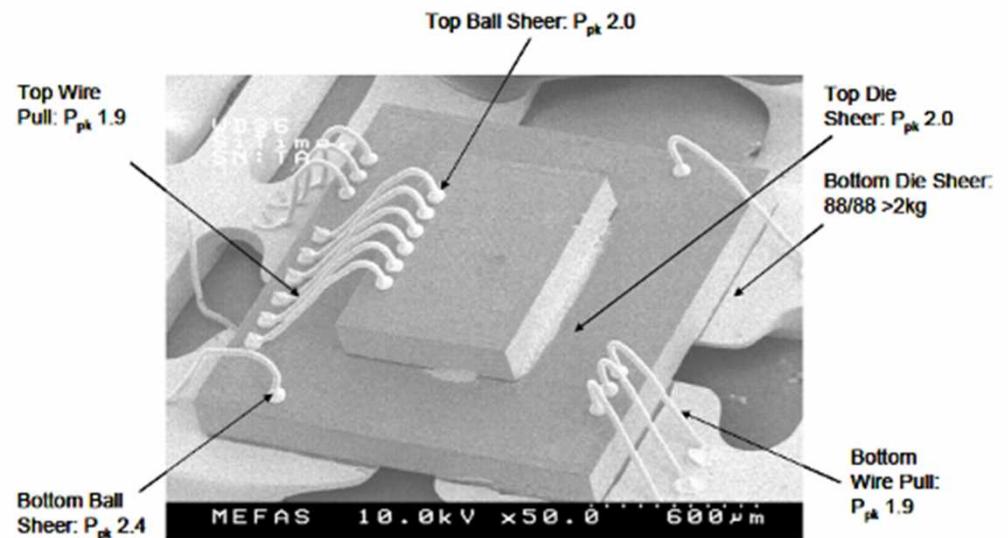
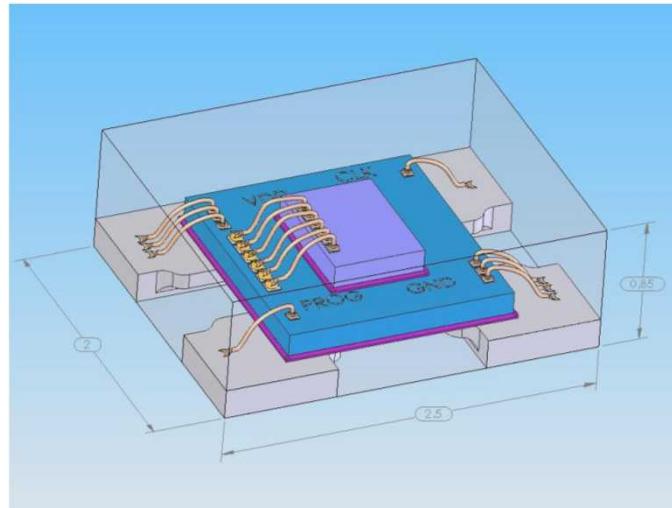
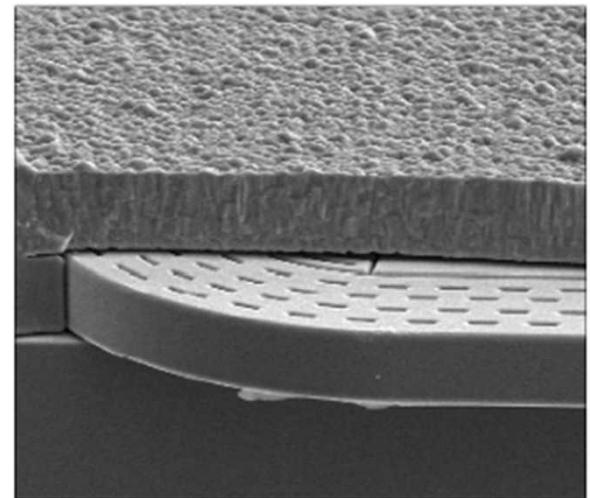
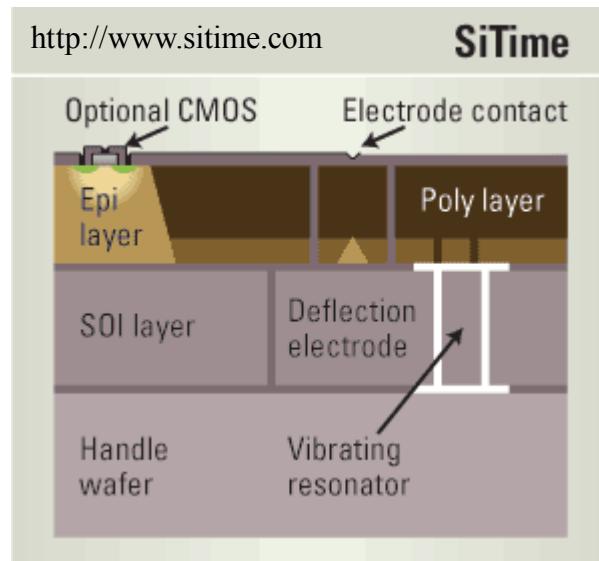


Figure 6. iMEMS accelerometer in surface mount package

SiTime Micro-Resonator

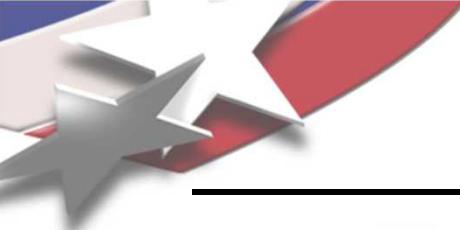
<http://www.sitime.com>

SiTime

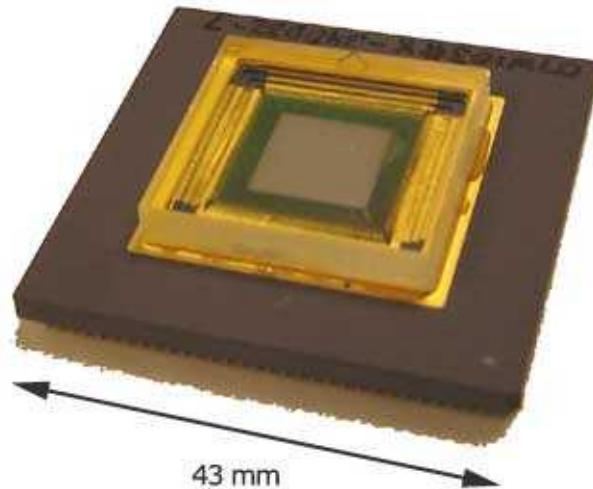


Cleanliness and Hermeticity

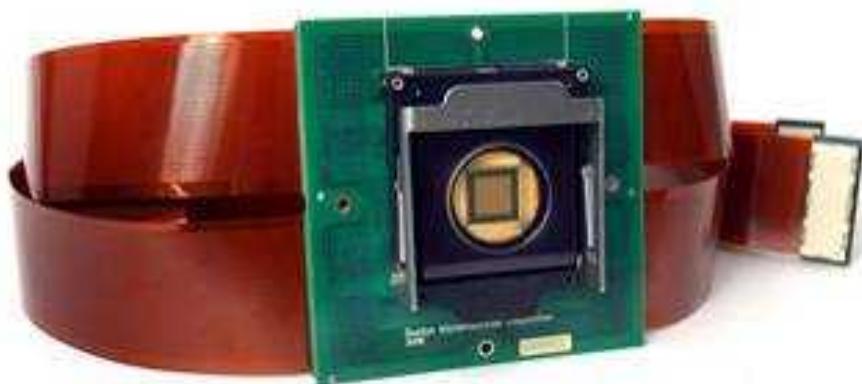
Integration with CMOS



Optical MEMS

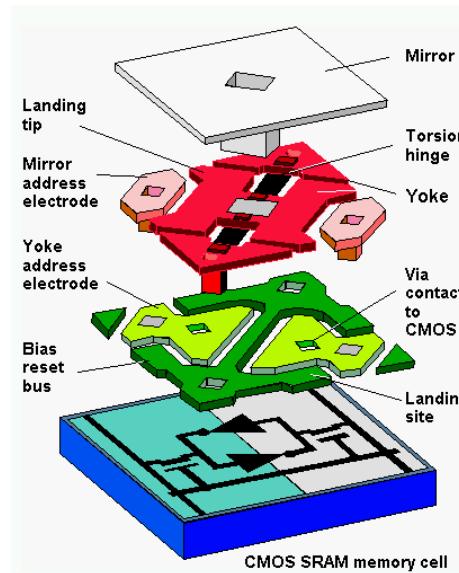


<http://www.bostonmicromachines.com>

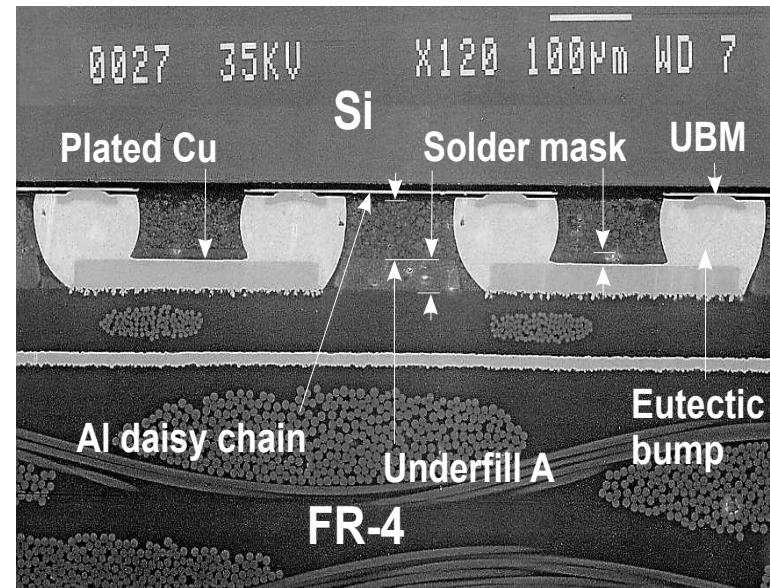
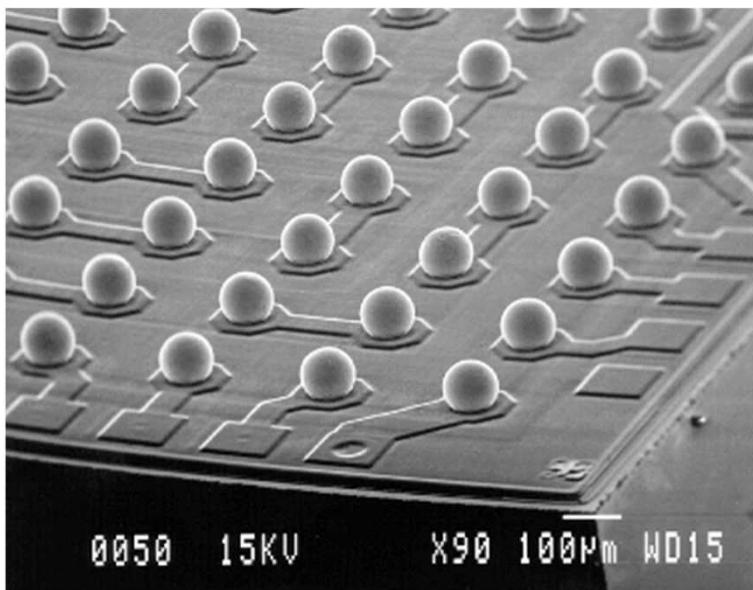


MEMS Specific Inputs/Outputs (optical)

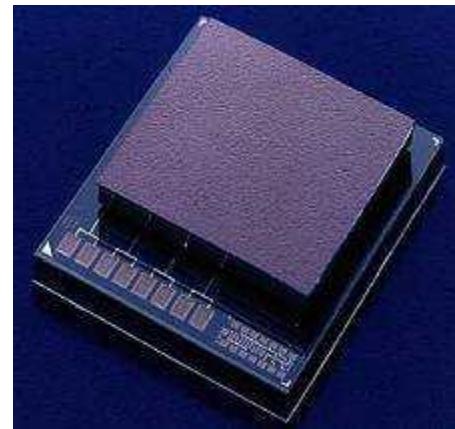
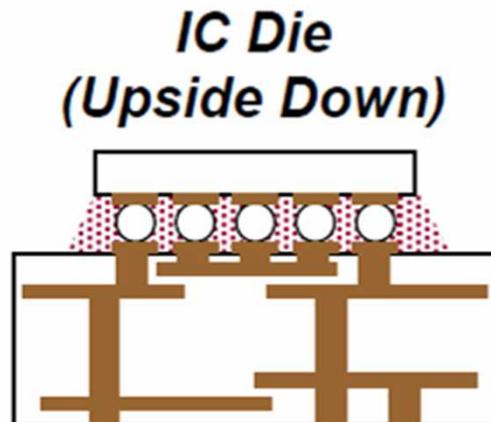
http://



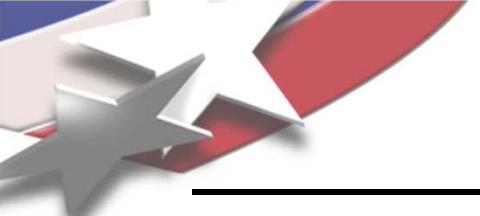
Flip-chip bonding/Integration



**Solder Balls
With Underfill**



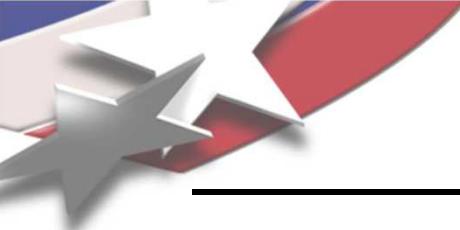
<http://www.wtec.org>



Testing Considerations

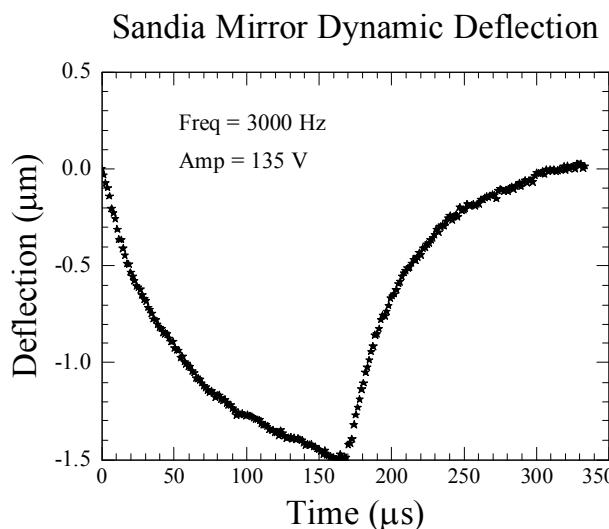


- Testing performed at:
 - Wafer (automated electrical tests)
 - Die
 - Package (full system tests, sometimes required for MEMS I/O)
- MEMS Specific Concerns
 - **Test for function, durability, and reliability in various environments**
 - Shock and vibration
 - Thermal (and thermal stresses)
 - Exposed ambient (pressure and flow sensors, optical, package environment)
 - Radiation
- **As with Packaging, testing is as varied as the application**
 - Optical (mirror arrays)
 - Fluidic (gas or liquid)
 - Electrical (RF MEMS)
 - Acceleration/vibration/shock (accelerometers)

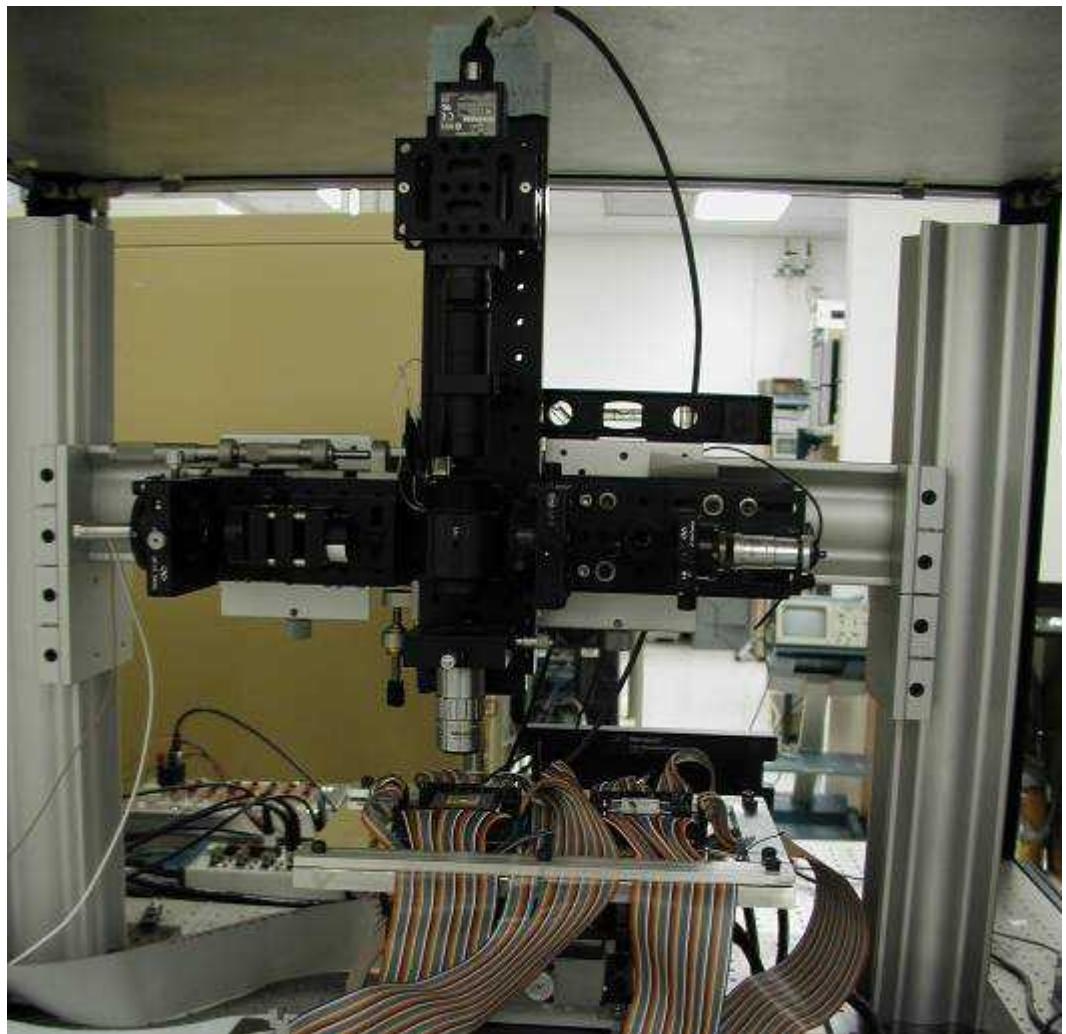


Different applications drive new capability development

Custom built long working distance stroboscopic interferometer used to measure mirror stroke at operating frequency

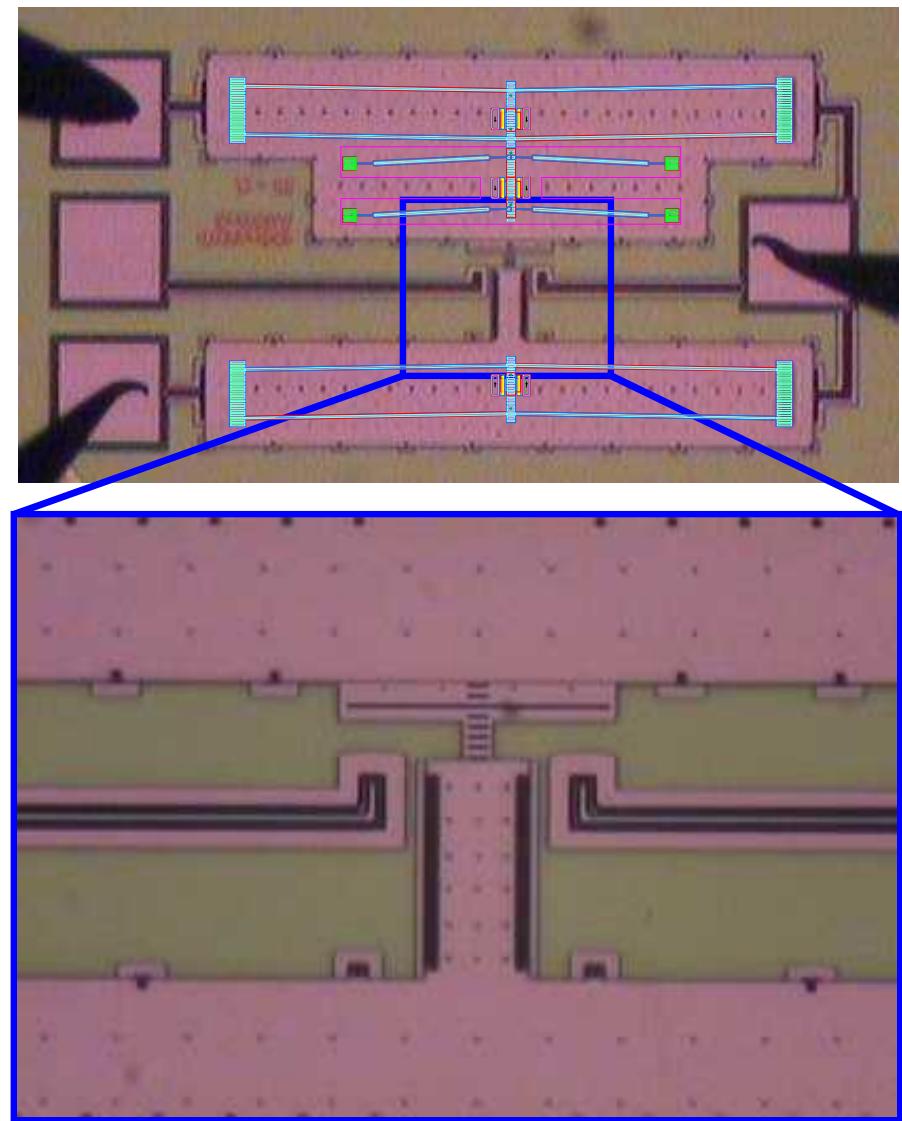
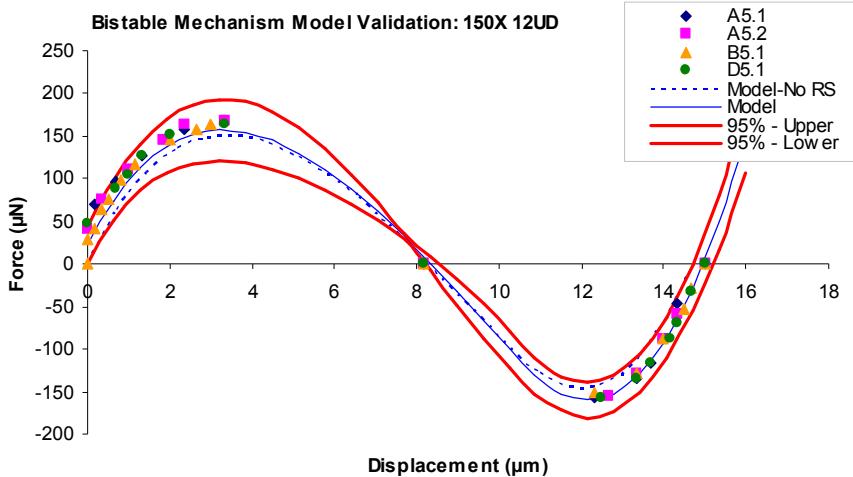


(A. Corwin)

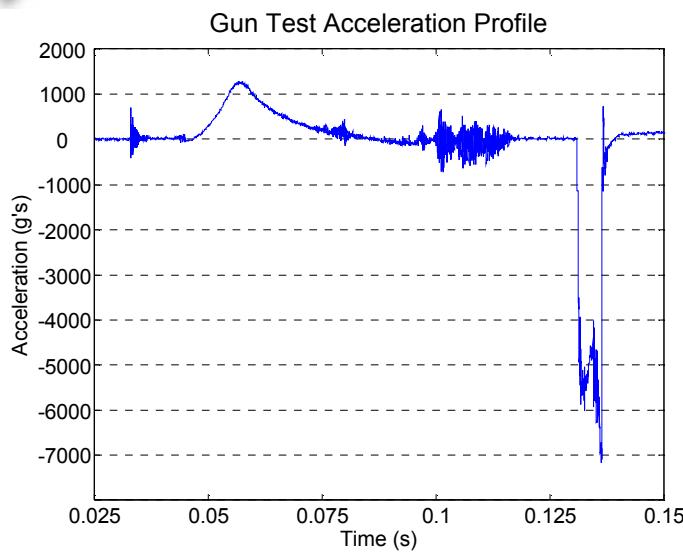


Example: MEMS Latching DC Relay

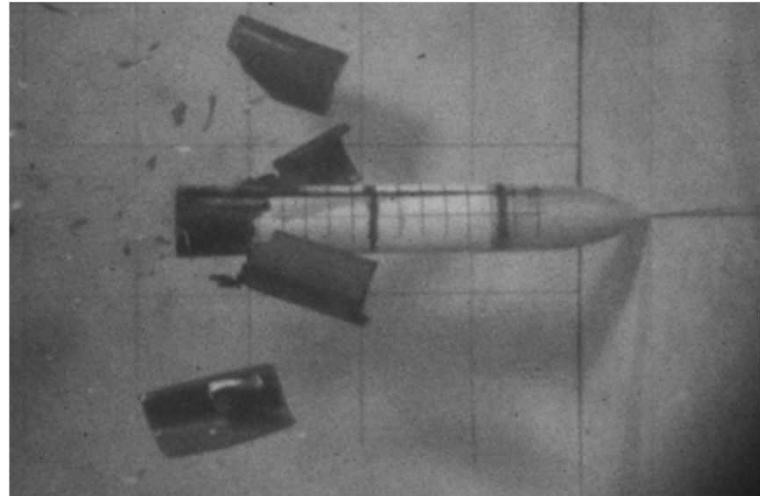
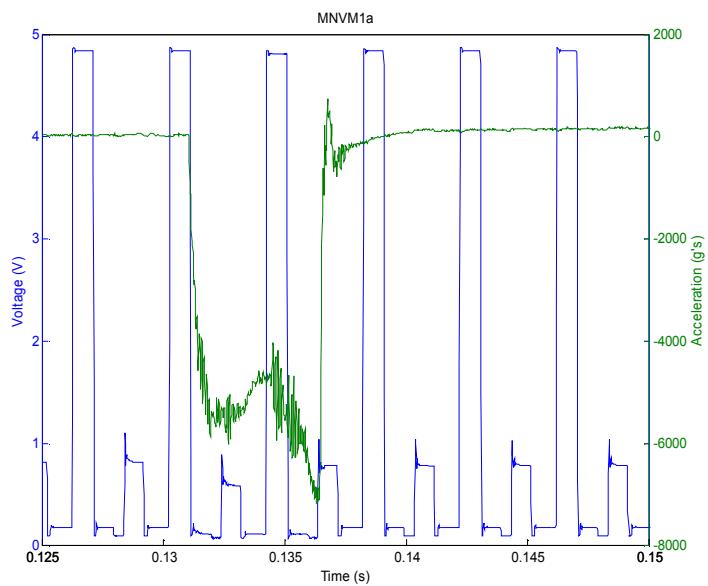
- Purpose: Develop a low power, shock/rad hardened, latching DC relay
- Technical Challenges
 - Performance of metal contacts with cycle count, both hot and cold switched.

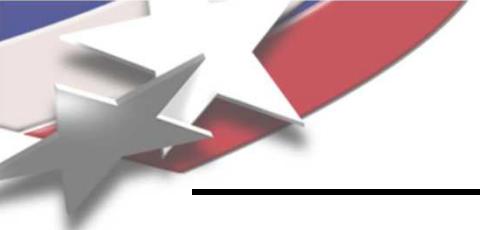


Penetrator Test Results



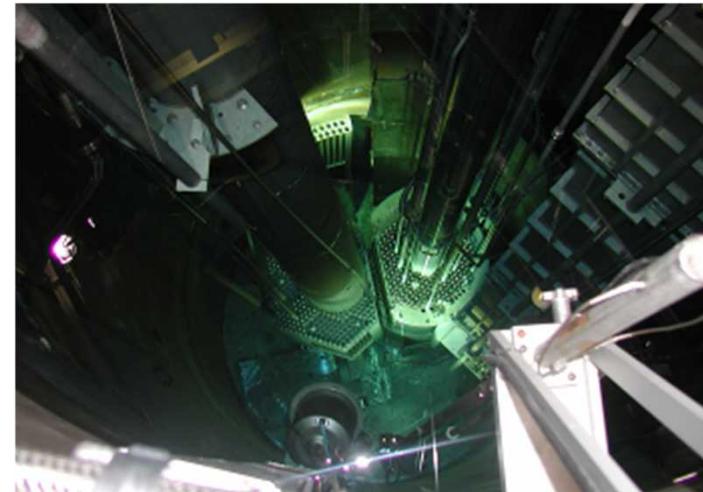
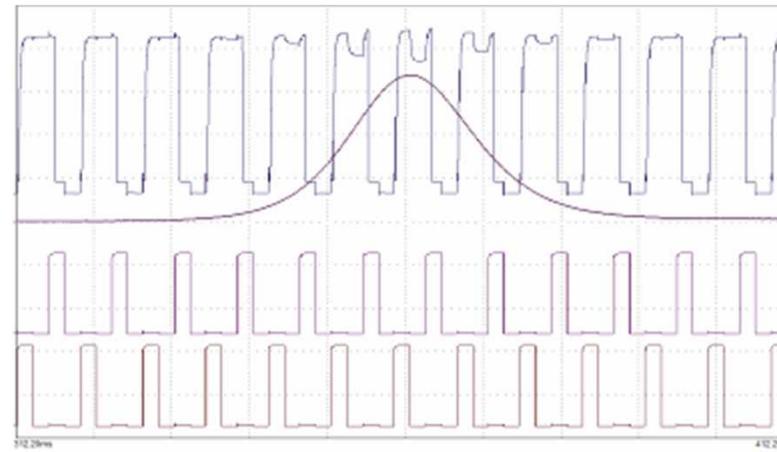
**Impact at
7200 g's
over 5.5
milliseconds**

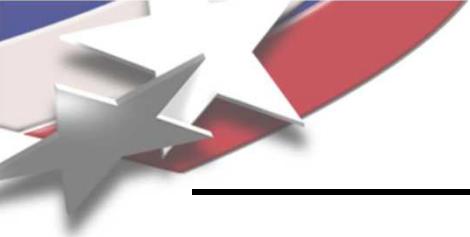




ACRR Radiation Testing

- Operated through both a max-pulse and a steady-state run free-field.
 - 16.5 Mrad(Si) total dose at steady-state
 - 100 Mrad(Si)/s peak dose rate from pulse
 - 1×10^{16} n/cm² max fluence





Questions?

**Michael S. Baker
Sandia National Laboratories
msbaker@sandia.gov**

- 40-80 people
- Govt. technical professionals, non MEMS.
Includes defense and security.
- Give thorough technical and historical background as well as review of state of art, relevant research, production, or use trends.
- 25 minute talk. Half intro/background and general observations. Then own research. 10 minutes additional time at end for questions.

- **General topics**
 - Existing or potential impacts for national security/defense
 - R&D status and outlook. What's coming down the pipe esp. for defense.
- **Packaging and testing**
 - Unique packaging requirements for mems
 - Robustness and reliability
 - Case studies as examples of unique.